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Front Matter: Volume 11783

, "Front Matter: Volume 11783," Proc. SPIE 11783, Modeling Aspects in Optical Metrology VIII, 1178301 (30 June 2021); doi: 10.1117/12.2603205

SPIE.

Event: SPIE Optical Metrology, 2021, Online Only

PROCEEDINGS OF SPIE

Modeling Aspects in Optical Metrology VIII

**Bernd Bodermann
Karsten Frenner**
Editors

**21–25 June 2021
Online Only, Germany**

Sponsored by
SPIE

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European Optical Society
German Scientific Laser Society (Wissenschaftliche Gesellschaft Lasertechnik e.V.)

Published by
SPIE

Volume 11783

Proceedings of SPIE 0277-786X, V. 11783

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Modeling Aspects in Optical Metrology VIII, edited by Bernd Bodermann
Karsten Frenner, Proc. of SPIE Vol. 11783, 1178301 · © 2021 SPIE
CCC code: 0277-786X/21/\$21 · doi: 10.1117/12.2603205

Proc. of SPIE Vol. 11783 1178301-1

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Author(s), "Title of Paper," in *Modeling Aspects in Optical Metrology VIII*, edited by Bernd Bodermann, Karsten Frenner, Proc. of SPIE 11783, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510644007

ISBN: 9781510644014 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time)

SPIE.org

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